

Abstract of the Disclosure

SUBSTRATE DEFECT INSPECTION APPARATUS, METHOD OF
ADJUSTING SENSITIVITY PARAMETER VALUE FOR SUBSTRATE
5 DEFECT INSPECTION, AND NON-TRANSITORY STORAGE MEDIUM

A method of adjusting a sensitivity parameter value for substrate defect inspection used in a substrate defect inspection apparatus compares, for each pixel value of a selected virtual inspection substrate, using reference
10 pixel data to be used after adjustment, the deviation amount from an allowable range corresponding to the position thereof and the sensitivity parameter value before the adjustment when each pixel value is deviated from the allowable range, and updates the deviation amount as a new sensitivity parameter value when the deviation amount exceeds the sensitivity parameter
15 value and a difference between the deviation amount and the sensitivity parameter value is equal to or less than a threshold value.

FIG. 13